

Supporting Information

Nucleation, Coalescence, and Thin Film Growth of Triflate-Based Ionic Liquids on ITO, Ag, and Au Surfaces

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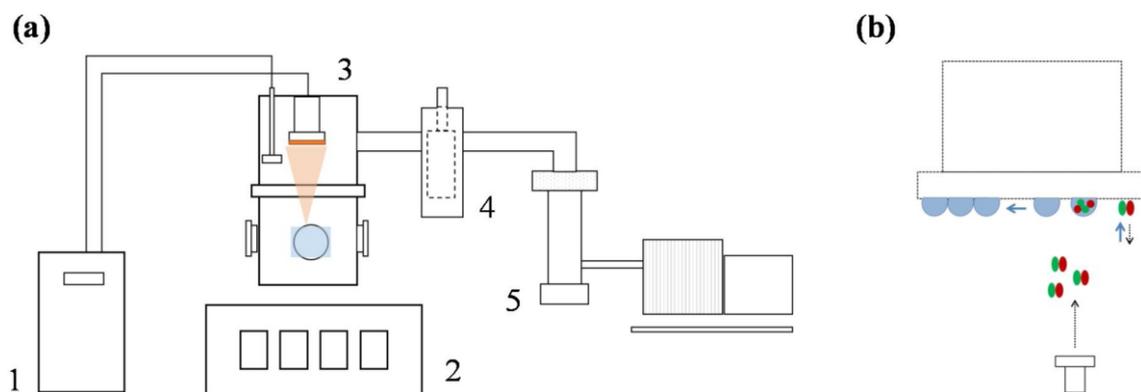


Figure S1. Schematic representation of the vapor deposition/vacuum thermal evaporation methodology: (a) ThinFilmVD apparatus (1 – cooling system, 2 – instrumentation box, 3 – vacuum chamber, 4 – $N_2(l)$ metallic trap, 5 – vacuum pumping system); (b) schematic detail of the PVD of ionic liquids by vacuum thermal evaporation from a Knudsen cell. More details: *Appl. Surf. Sci.*, 2018, 428, 242 and *J. Chem. Eng. Data*, 2015, 60, 3776.

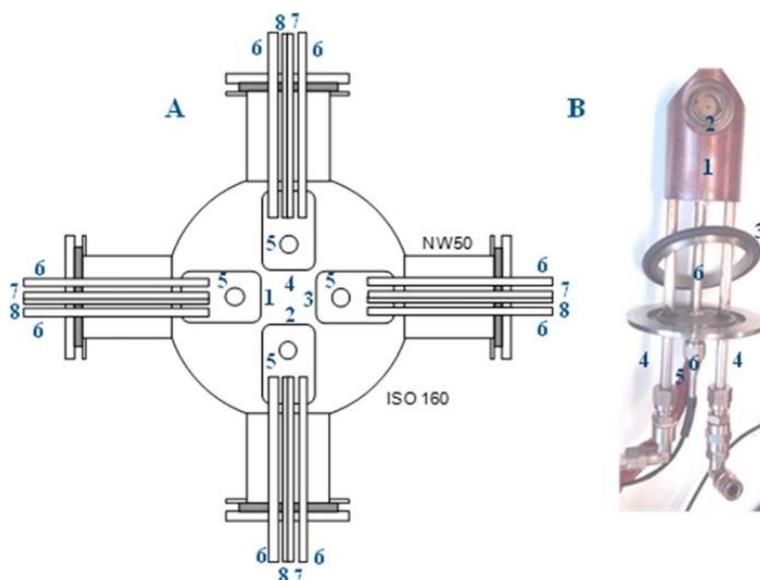


Figure S2. A – Schematic representation of the ovens of the ThinFilmVD apparatus: 1, 2, 3, 4 – individual copper ovens; 5 – cavity of the Knudsen cell screwing; 6 – air cooling tube; 7 – heater; 8, – Pt100 sensor; B – Image of an individual oven (top view): 1 – copper block; 2 – Knudsen cell; 3 – Viton O-ring; 4 – cooling system; 5 – heater; 6 – Pt100. More details: *J. Chem. Eng. Data*, 2015, 60, 3776.

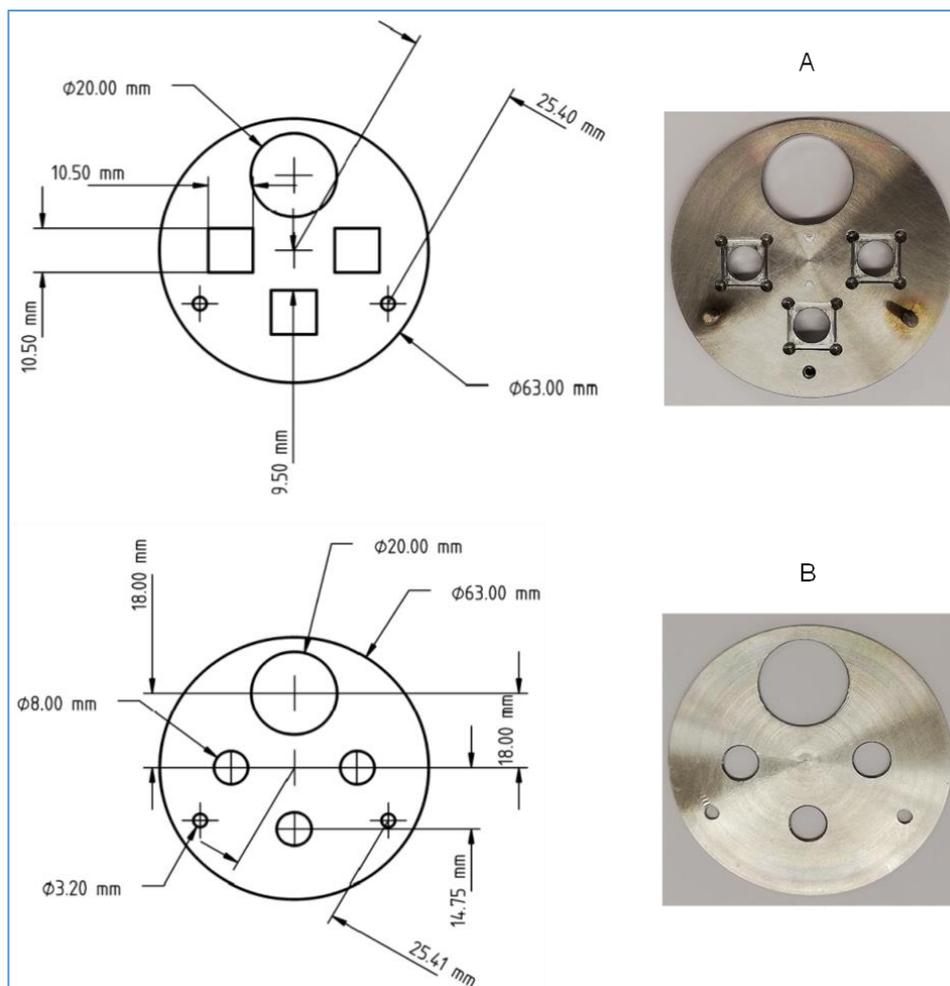


Figure S3. Schematic representation (left) and images (right) of the substrate support system. The support was used for the simultaneous deposition of each ionic liquid on three different surfaces: ITO/glass; Ag/ITO/glass; Au/ITO/glass.

PVD of Ionic Liquids

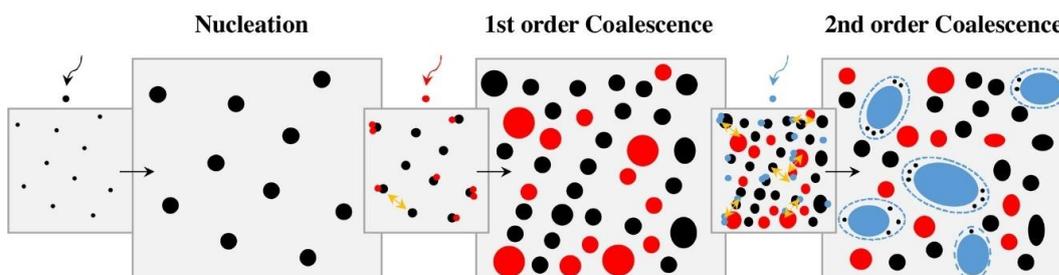


Figure S4. Illustration of the mechanisms of nucleation and growth of ionic liquid films: minimum free area to promote nucleation (MFAN); first-order coalescence; second-order coalescence. More details: *Appl. Surf. Sci.*, 2018, 428, 242.

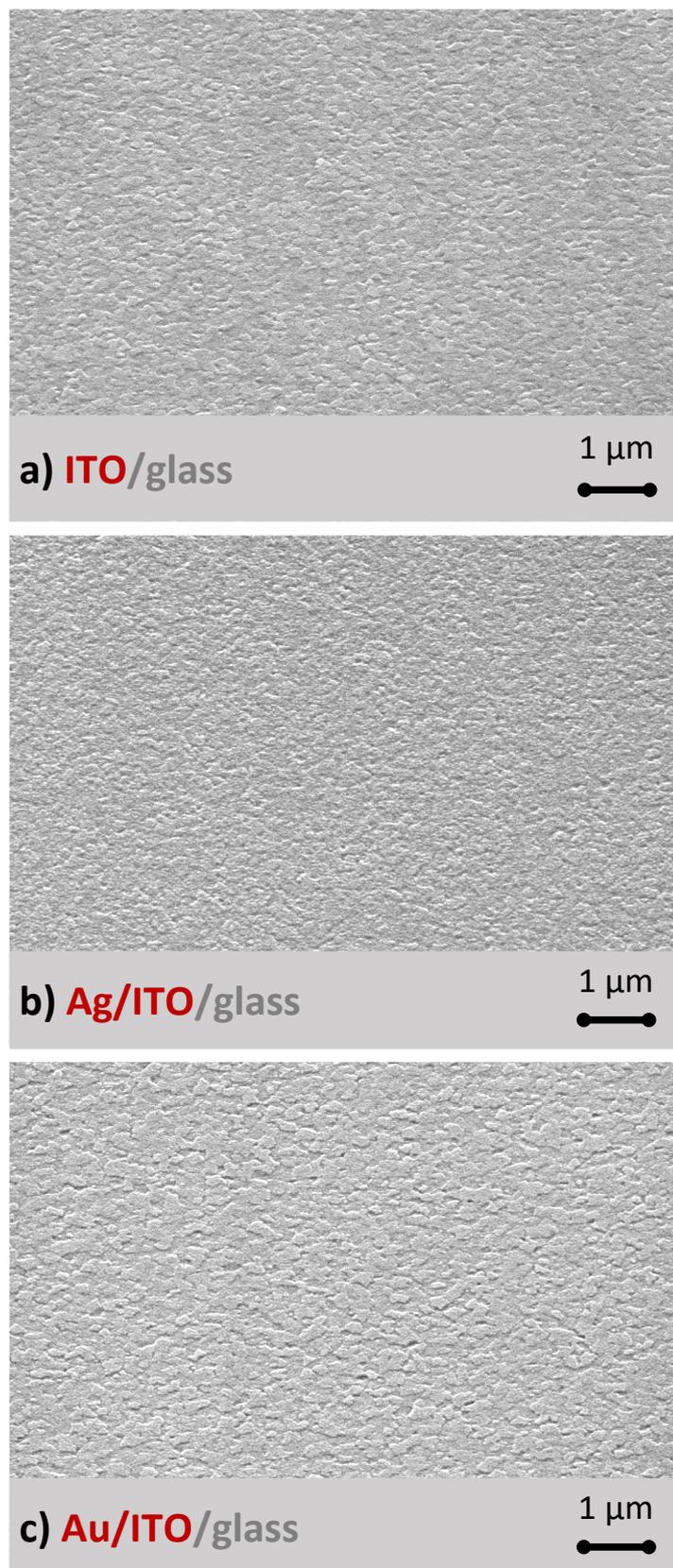


Figure S5. Morphology of the substrates: indium tin oxide (ITO)/glass surface (a); silver(Ag)/ITO/glass surface (b); gold(Au)/ITO/glass surface. Micrographs were acquired through high-resolution scanning electron microscopy (SEM) by using a secondary electron detector (SED). Lateral views at 45° were obtained with a magnification of 25000×.

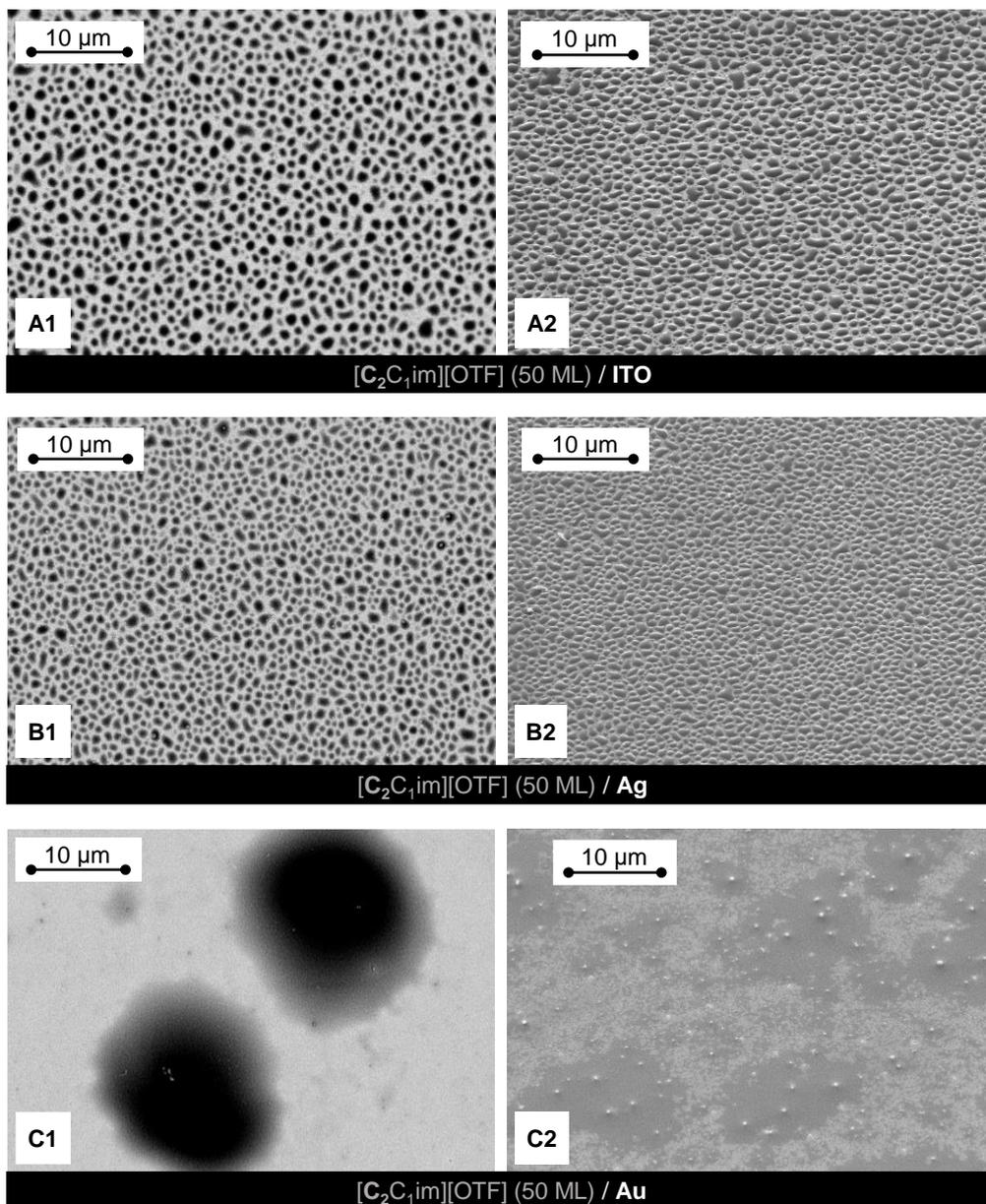


Figure S6. Micrographs acquired through high-resolution scanning electron microscopy of vapor-deposited $[C_2C_{1im}][OTF]$ (50 monolayers, ML) onto surfaces of indium tin oxide (ITO)/glass (A1, A2), silver (Ag)/ITO (B1, B2), and gold(Au)/ITO (C1, C2). Top views (5000 \times) obtained by backscattered electron (A1, B1, C1) imaging, and lateral views at 45 $^\circ$ (5000 \times) obtained by secondary electron imaging (A2, B2, C2).

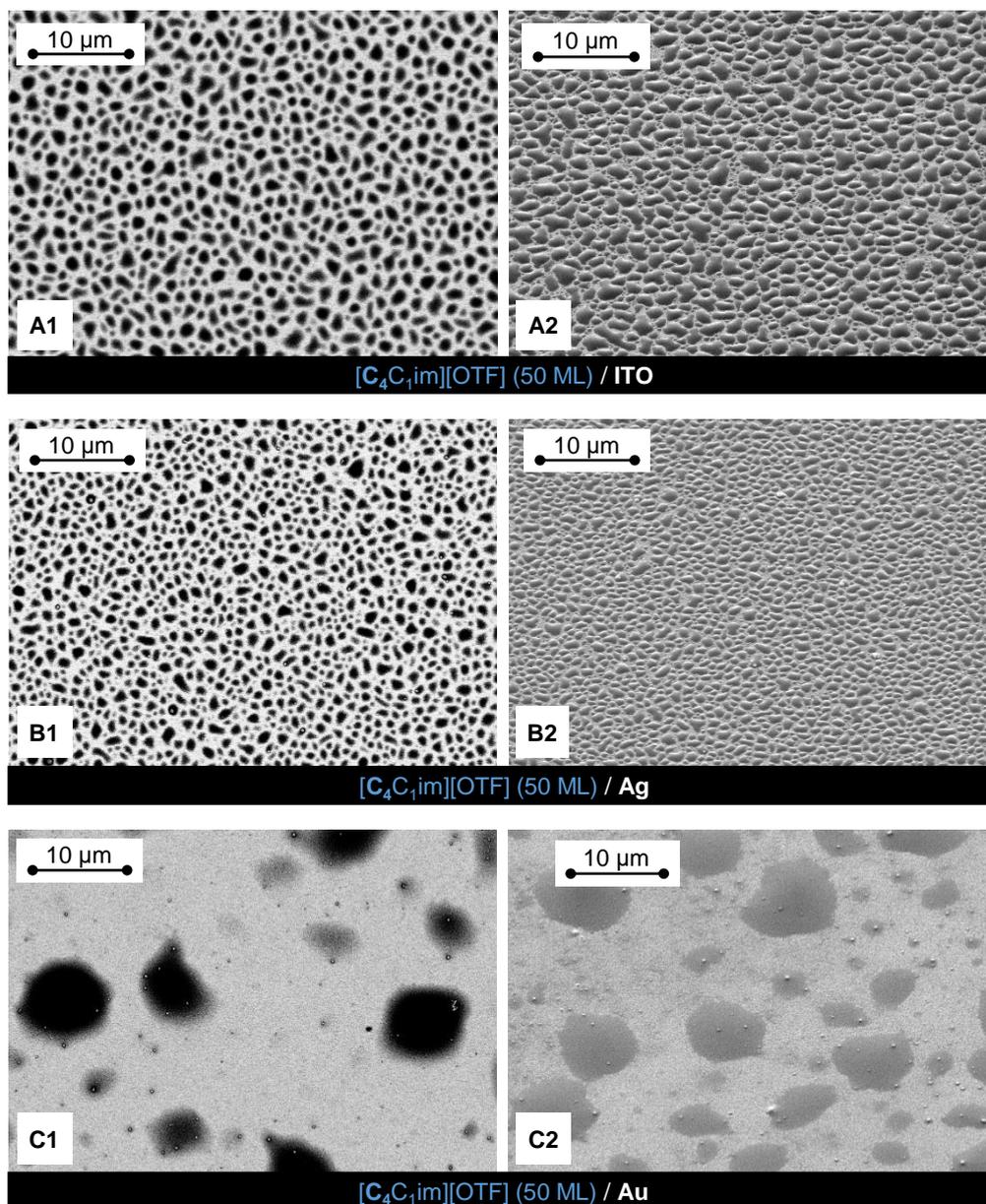


Figure S7. Micrographs acquired through high-resolution scanning electron microscopy of vapor-deposited $[C_4C_{1im}][OTF]$ (50 monolayers, ML) onto surfaces of indium tin oxide (ITO)/glass (A1, A2), silver (Ag)/ITO (B1, B2), and gold(Au)/ITO (C1, C2). Top views (5000 \times) obtained by backscattered electron (A1, B1, C1) imaging, and lateral views at 45 $^\circ$ (5000 \times) obtained by secondary electron imaging (A2, B2, C2).

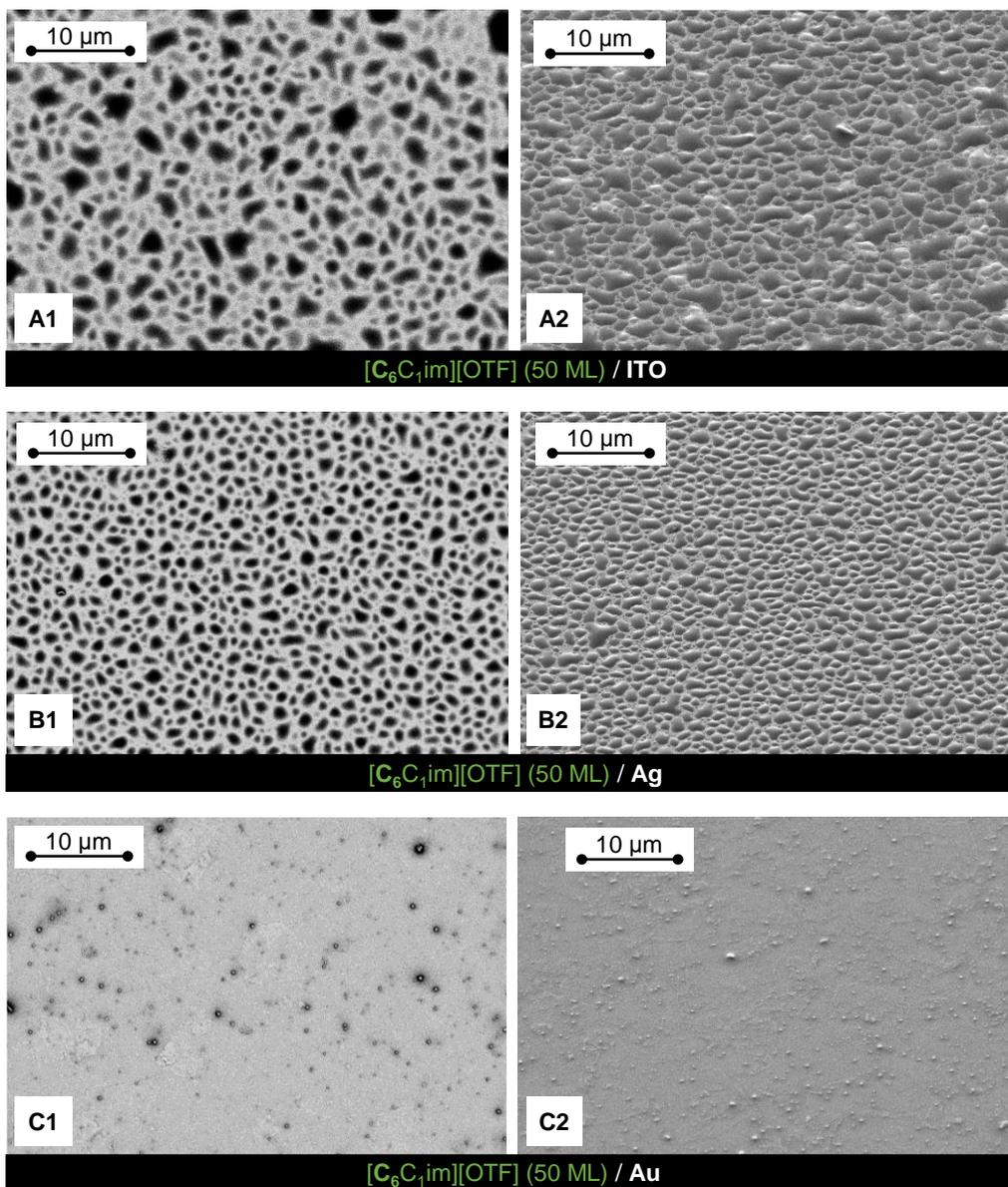


Figure S8. Micrographs acquired through high-resolution scanning electron microscopy of vapor-deposited $[\text{C}_6\text{C}_{1\text{im}}][\text{OTF}]$ (50 monolayers, ML) onto surfaces of indium tin oxide (ITO)/glass (A1, A2), silver (Ag)/ITO (B1, B2), and gold(Au)/ITO (C1, C2). Top views (5000 \times) obtained by backscattered electron (A1, B1, C1) imaging, and lateral views at 45 $^\circ$ (5000 \times) obtained by secondary electron imaging (A2, B2, C2).

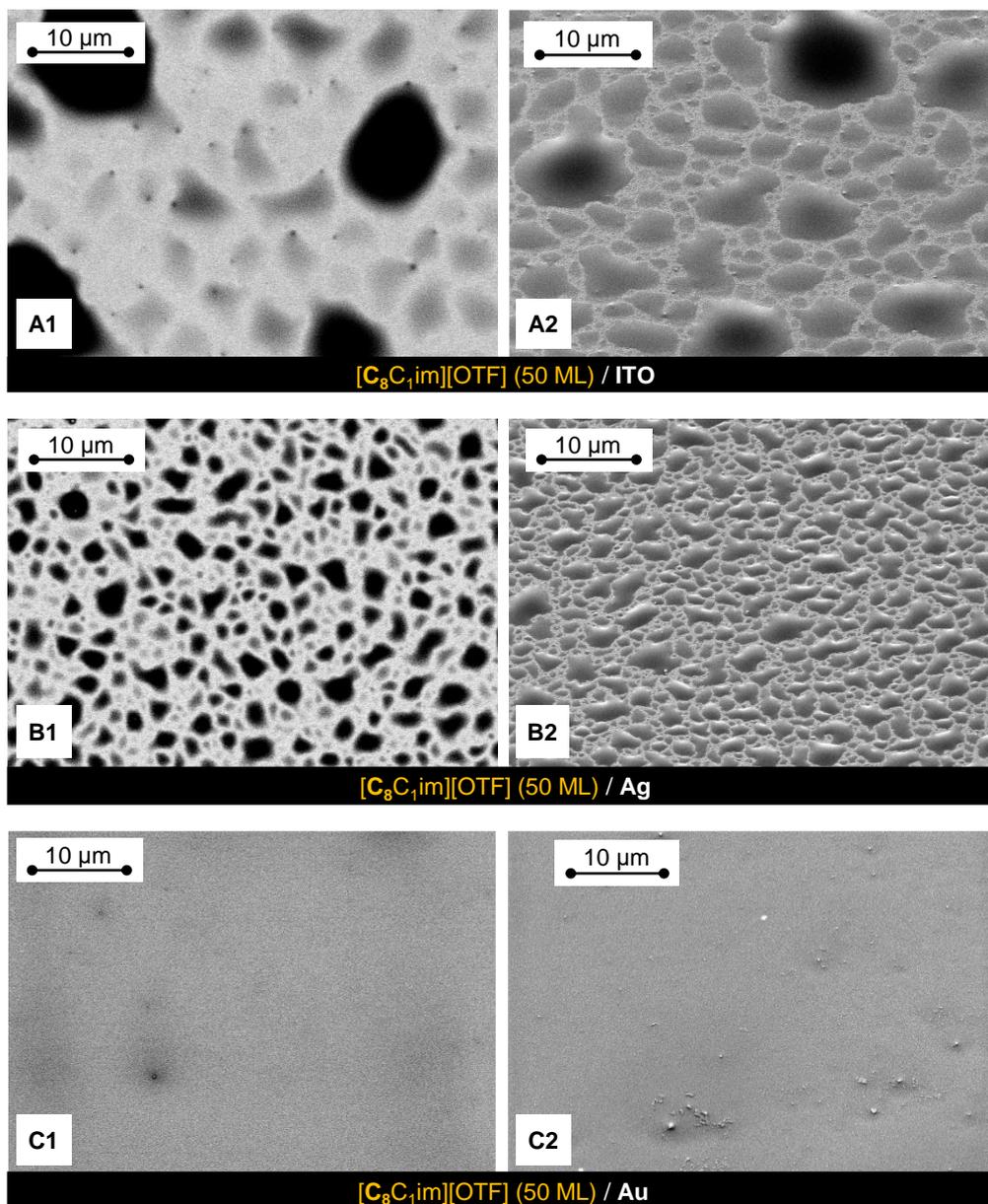


Figure S9. Micrographs acquired through high-resolution scanning electron microscopy of vapor-deposited $[C_8C_{1im}][OTF]$ (50 monolayers, ML) onto surfaces of indium tin oxide (ITO)/glass (A1, A2), silver (Ag)/ITO (B1, B2), and gold(Au)/ITO (C1, C2). Top views (5000 \times) obtained by backscattered electron (A1, B1, C1) imaging, and lateral views at 45 $^\circ$ (5000 \times) obtained by secondary electron imaging (A2, B2, C2).

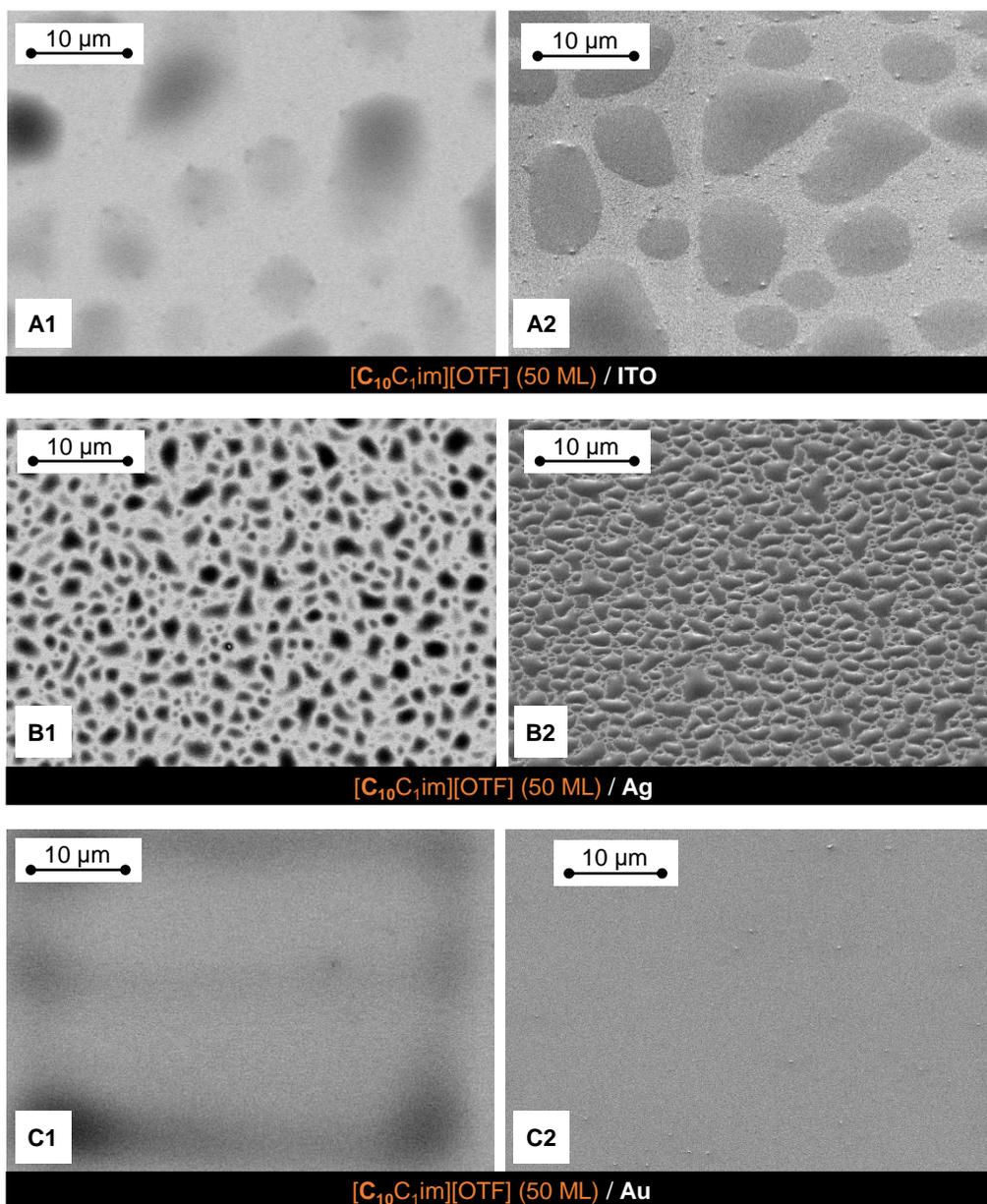


Figure S10. Micrographs acquired through high-resolution scanning electron microscopy of vapor-deposited $[C_{10}C_{1im}][OTF]$ (50 monolayers, ML) onto surfaces of indium tin oxide (ITO)/glass (A1, A2), silver (Ag)/ITO (B1, B2), and gold(Au)/ITO (C1, C2). Top views ($5000\times$) obtained by backscattered electron (A1, B1, C1) imaging, and lateral views at 45° ($5000\times$) obtained by secondary electron imaging (A2, B2, C2).

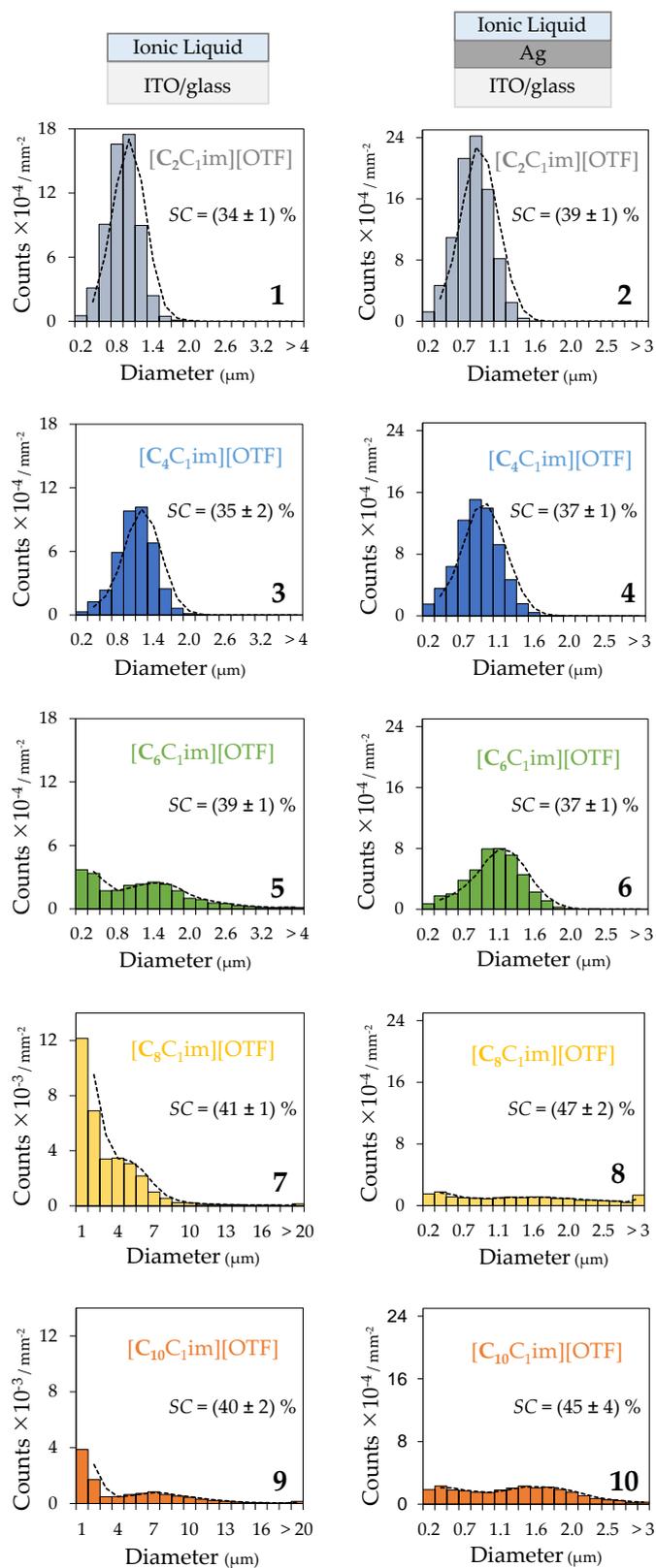


Figure S11. Droplet size distribution of vapor-deposited ionic liquids (50 monolayers, ML) onto ITO/glass (graphs on the left) and Ag/ITO/glass surfaces (graphs on the right): [C₂C₁im][OTF] (1,2); [C₄C₁im][OTF] (3,4); [C₆C₁im][OTF] (5,6); [C₈C₁im][OTF] (7,8); [C₁₀C₁im][OTF] (9,10). Values for the surface coverage (SC) are marked in each graph. The ionic liquids were deposited under the same experimental procedure and setup.

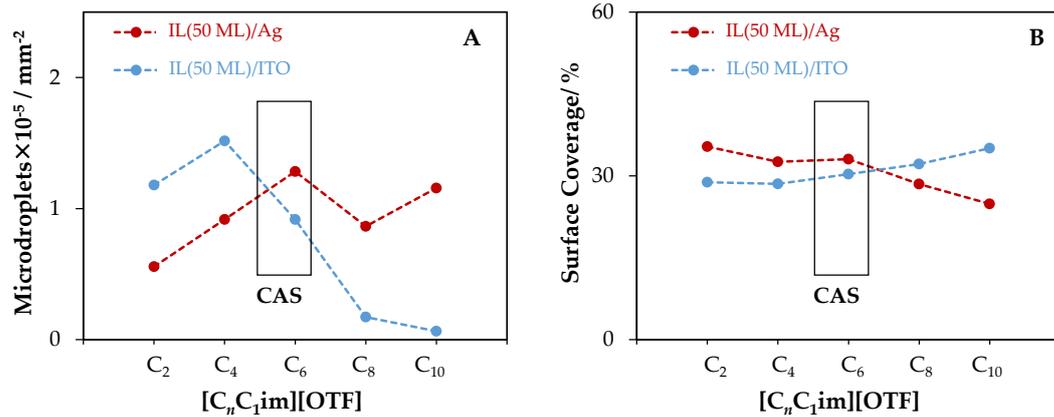


Figure S12. Schematic representation of the number of ionic liquid microdroplets (diameter above 1 μm) formed per mm^2 of surface area (graph A) and the respective surface coverage of those microdroplets (graph B) as a function of each ionic liquid in the $[\text{C}_n\text{C}_1\text{im}][\text{OTF}]$ series.

Table S1. Experimental conditions for the physical vapor deposition/thermal evaporation of each ionic liquid: effusion temperature (T_{eff}); equilibrium vapor pressure (EVP); mass flow rate at the Knudsen effusion cell orifice (Φ (Knudsen cell)); mass flow rate at the substrate surface (Φ (QCM)) and corresponding deposition rate in $\text{\AA}\cdot\text{s}^{-1}$; geometric factor; deposition time; thin film thickness (nm and ML).

Precursor	T_{eff}	EVP	Φ (Knudsen cell)	Φ (QCM)	Geometric factor	Deposition rate	Deposition time	Thickness
	K	Pa	$\mu\text{g}\cdot\text{cm}^{-2}\cdot\text{s}^{-1}$	$\text{ng}\cdot\text{cm}^{-2}\cdot\text{s}^{-1}$		$\text{\AA}\cdot\text{s}^{-1}$	min	ML
[C_nC_{1im}][OTF] (50 ML) / substrate substrates: Au/ITO; Ag/ITO; ITO								
[C ₂ C _{1im}][OTF]	513.2			4.4 ± 0.7		0.32 ± 0.05	≈ 18	
[C ₄ C _{1im}][OTF]	513.2			3.4 ± 0.7		0.26 ± 0.05	≈ 23	
[C ₆ C _{1im}][OTF]	513.2	≈ 0.1	≈ 30	4.1 ± 0.6	$\approx 1 \times 10^{-4}$	0.33 ± 0.05	≈ 19	50
[C ₈ C _{1im}][OTF]	523.2			3.1 ± 0.6		0.26 ± 0.05	≈ 25	
[C ₁₀ C _{1im}][OTF]	523.2			3.5 ± 0.6		0.30 ± 0.05	≈ 23	